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Bib Data Sheet

CONFIRMATION NO. 3205

SERIAL NUMBER 09/187,551	FILING DATE 11/05/1998 RULE	CLASS 427	GROUP ART UNIT 1762	ATTORNEY DOCKET NO. AM524R1/T289
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APPLICANTS

KATSUYUKI MUSAKA, INBA, JAPAN;

SHINSUKE MIZUNO, INBA, JAPAN;

** CONTINUING DATA *****

This application is a REI of 08/259,584 06/14/1994 PAT 5,571,571
which is a CIP of 08/184,331 01/19/1994 ABN

** FOREIGN APPLICATIONS *****

JAPAN 3-145070 06/16/1993

Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged	<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Examiner's Signature _____ Initials _____	STATE OR COUNTRY JAPAN	SHEETS DRAWING 9	TOTAL CLAIMS 26	INDEPENDENT CLAIMS 5
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ADDRESS

32588
APPLIED MATERIALS, INC.
2881 SCOTT BLVD. M/S 2061
SANTA CLARA, CA
95050

TITLE

METHOD OF FORMING A THIN FILM FOR A SEMICONDUCTOR DEVICE

FILING FEE RECEIVED 1168	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees
		<input type="checkbox"/> 1.16 Fees (Filing)
		<input type="checkbox"/> 1.17 Fees (Processing Ext. of time)
		<input type="checkbox"/> 1.18 Fees (Issue)
		<input type="checkbox"/> Other _____
		<input type="checkbox"/> Credit

SERIAL NUMBER	FILING DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
09/187,551 REISSUE	11/05/98	427	1762	AM524R1/T289
APPLICANT KATSUYUKI MUSAKA, INBA, JAPAN; SHINSUKE MIZUNO, INBA, JAPAN. **CONTINUING DOMESTIC DATA***** VERIFIED THIS APPLN IS A RE OF 08/259,584 06/14/94 PAT 5,571,571 WHICH IS A CIP OF 08/184,331 01/19/94 ABN **371 (NAT'L STAGE) DATA***** VERIFIED **FOREIGN APPLICATIONS***** VERIFIED JAPAN 3-145070 06/16/93				
Foreign Priority claimed 35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No <input type="checkbox"/> Met after Allowance		STATE OR COUNTRY JPX	SHEETS DRAWING 9	TOTAL CLAIMS 26
Verified and Acknowledged Examiner's Initials _____		INDEPENDENT CLAIMS 5		
ADDRESS TOWNSEND AND TOWNSEND AND CREW 379 LYTTON AVE PALO ALTO CA 94301		Patent Counsel, MIS 2061 Legal Affairs Department Applied Materials, Inc. P.O. Box 450A Santa Clara, CA 95052		
TITLE METHOD OF FORMING A THIN FILM FOR A SEMICONDUCTOR DEVICE				
FILING FEE RECEIVED \$1,168	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT NO. _____ for the following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	